Specialty Gas Equipment



PRESSURE REGULATORS

Electronic Service



Design Features

32 Ra Internal Surface Finish Unique Patented Compression Member loads the seal to the body without requiring a threaded nozzle or additional seal to atmosphere. Meets NACE Standard MR0175 Captured Bonnet

allows for safety venting.

Specifications

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Max Rated Inlet Pressure	4,000 psig (2.76 bar)			
Outlet Pressure Range	1–30, 2–60, 3–100, 10–250 psig			
Cv	0.06			
Ambient Operating Temperature	–40° F to 150° F (–38° C to 65° C)			
Designed Leak Rate	2 x 10-8 scc/sec (helium)			
Weight	1.5 lbs (0.7 kg)			
Ports	1/4" Face Seal			
Inlet	1/4" Female Face Seal			
Outlet	1/4" Male Face Seal			
Gauge Ports	1/4" Male Face Seal			
Gauge Size	2" diameter			
Supply Pressure Effect	0.6/100 psi			

Materials			
Body	316L Stainless Steel		
Bonnet	Nickel Plated Brass		
Seat	PCTFE		
Diaphragm	Hastelloy C-22®		
Gauges	2" Female Face Seal		
Filter	None		
Seals	PTFE		
Poppet	Elglloy®		
Poppet Spring	lconel®		
Carrier	Stainless Steel		
Back-up washer	316L Stainless Steel		
Back-up O-ring	KFM		

Ordering Information					
Product Number	Material	Max Inlet Pressure (psig)	Max Outlet Pressure (psig)	Inlet Gauge Range (psig)	Outlet Gauge Range (psig)
Y11-HP900A(CGA)	316L Stainless Steel	4,000	30	0-4,000	0–60
Y11-HP900B(CGA)	316L Stainless Steel	4,000	60	0-4,000	0-100
Y11-HP900D(CGA)	316L Stainless Steel	4,000	100	0-4,000	0–200
Y11-HP900F(CGA)	316L Stainless Steel	4,000	250	0-4,000	0-400

Ultra-High-Purity Single-Stage

Description: The Airgas[®] Model 900 Ultra-High-Purity Single-Stage Regulators are internally threadless pressure regulator specifically designed for instrument/analyzer and semiconductor applications. This regulator's unique carrier design disperses gas uniformly through the regulator to improve purging. The seat material meets the requirements for corrosive and inert gases.

These regulators are all orbitally welded with highpurity face seal connections and have a 32 Ra internal surface finish. Optional 10 Ra electropolished.

Instrument applications include gas management systems in petrochemical/refineries and process analyzer systems. Semiconductor applications include general-purpose gas management (air, condensed dry air (CDA), and plant nitrogen).

This regulator is a high-pressure ultra-high-purity regulator.